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Substitute for form 1449A/PTO INFORMATION DISCLOSURE STATEMENT BY APPLICANT <i>(use as many sheets as necessary)</i>		Complete if Known	
Sheet	1	of	1
		Application Number	T.B.A.
		Filing Date	Even Date Herewith
		First Named Inventor	Wolfgang M.J. Hofmann
		Group Art Unit	1772
		Examiner Name	
		Attorney Docket Number	Hofmann

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
PCD		5,198,390		MacDonald	03/03/1993	
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Examiner Signature		Date Considered	12/10/2005
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			Examiner Name	
Sheet 1	of 1	Attorney Docket Number	Hofmann	

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Examiner Signature	<i>Robert Charles Davis</i>	Date Considered	12/10/2005
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS			
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MD		CHANG, T.H.P., Kern, D.P., Muray, L.P.; Microminiaturization of electron optical systems; J. Vacuum Science & Technology B, vol. 8, pp. 1698-1705, 1990	
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Examiner Signature	<i>Dorothy Chahin</i>	Date Considered	12/10/2005
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WD		MACDONALD, N.C.; SCREAM Microelectromechanical systems; Microelectronic Engineering, vol. 32, pp. 49-73, Sept. 1996	
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Examiner Signature	<i>Deborah L. Davis</i>	Date Considered	12/10/2005
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